



IFW

PATENT
29936/39478

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of: Dong Joon Kim

Serial No.: 10/636,168

Filed: August 7, 2003

For: Method of Forming Metal Line in
Semiconductor Device

Group Art Unit: 2818

Examiner: David Nhu

I hereby certify that this paper and the documents referred to as enclosed therewith are being deposited with the United States Postal Service as first class mail, postage prepaid, on **September 13, 2004**, in an envelope addressed to Commissioner for Patents, P.O. Box 1450, Alexandria, Virginia 22313-1450.

Michael R. Hull
Reg. No. 35,902
Attorney for Applicant

COMMENT ON STATEMENT OF REASONS FOR ALLOWANCE AND AMENDMENT AFTER ALLOWANCE (37 CFR 1.312)

Commissioner for Patents
P.O. Box 1450
Alexandria, Virginia 22313-1450

Dear Commissioner:

In addition to the reasons for allowance set forth in the allowance papers that were mailed in connection with the present application, it is respectfully submitted that the claims are allowable for the additional reasons that the invention defined by the language of the claims is neither anticipated by, nor would have been obvious when taken as a whole in view of, the art of record.

Respectfully submitted,

MARSHALL, GERSTEIN & BORUN LLP
6300 Sears Tower
233 South Wacker Drive
Chicago, Illinois 60606-6357
(312) 474-9577

September 13, 2004

By: Michael R. Hull
Reg. No. 35,902